## **APPLICATION DATA SHEET**

Electronic Version 0.0.11 Stylesheet Version: 1.0

Publication Filing Type:

new-utility

Application Type:

utility

METHOD FOR DETERMINING A PRECEDING WAFER, METHOD FOR

Title of Invention:

DETERMINING A MEASURING WAFER, AND METHOD FOR

ADJUSTING THE NUMBER OF WAFERS

Legal Representative:

Attorney or Agent:

Donald R. Studebaker

Registration Number:

32815

**Continuity Data:** 

This application is a division of 10/431,513 2003-05-08 Pending

which is a division of 09/649,573 2003-05-08 ISSUE

Foreign Priority:

2000-160709

JP 2000-05-30

**Priority Claimed** 

Assignee (Publish): Matsushita Electronics Corporation

1-1, Saiwai-cho

Takatsuki-shi, 569-1193 Osaka JP

**INVENTOR(s)**:

Primary Citizenship:

Japanese

Given Name:

Hiroaki

Family Name:

**ISHIZUKA** 

Residence City:

Yawata-shi

**Residence Country:** 

ΙP

Address:

4-2D19-807, Otokoyama-sasatani, Yawata-shi, Kyoto

614-8372, Japan

Yawata-shi Kyoto, 614-8372 JP

Primary Citizenship:

**Japanese** 

Given Name:

Shigeru

Family Name:

Matsumoto

Residence City:

Higashiosaka-shi

Residence Country:

JΡ

Address:

6-7-38, Higashiishikiri-cho

Higashiosaka-shi, Osaka, 579-8011 JP